



Image

S&H Form: (2/01)
Attorney Docket No. 1082.1042

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hitoshi YAMADA, et al.

Application No.: 10/076,333

Group Art Unit: 2875

Confirmation No.: 2004

Filed: February 19, 2002

Examiner: Dalei Dong

For: GAS DISCHARGE TUBE AND METHOD FOR FORMING ELECTRON EMISSION
LAYER IN GAS DISCHARGE TUBE

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed January 16, 2004, applicants elect Claims 4-21
of Group II, with traverse.

Respectfully submitted,

STAAS & HALSEY LLP

Date: January 26, 2004

By: Paul I. Kravetz
Paul I. Kravetz
Registration No. 35,230

1201 New York Ave, N.W., Suite 700
Washington, D.C. 20005
Telephone: (202) 434-1500
Facsimile: (202) 434-1501